

## ABSTRACT

An apparatus and method for detecting foreign particle  
and defect on an object in detection by means of a laser beam,  
in which the laser beams of different wavelengths are irradiated  
onto the surface of the object in detection from different angles  
and the state of foreign particle and defect is separately detected  
according to the output level of the scattered light reflected  
from that surface. Further, it is arranged such that the scattered  
light reflected from the object onto which the laser beam is  
irradiated from the sole source or the plurality of sources is  
detected in plural directions, which detecting result is compared  
for the detection of the directivity of said scattered light  
in reflection.